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| Form PTO-1449 (Rev. 8-88) | Attorney Docket No. ILL02-023-DIV-US | Serial No. 10/670,585 |
| INFORMATION DISCLOSURE CITATION (Use several sheets if necessary) | Applicant: Chang Liu, et al. | |
| | Filing Date: September 25, 2003 | Group: 2881 |

| Examiner Initials* | | OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS |
|-----------------------|----|--|
| | | Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages |
| | C1 | Niklaus, F., "Void-Free Full Wafer Adhesive Bonding", presented at MEMS'00, Miyazaki, Japan, Jan. 23-27, 2000, pp. 323-328, Miyazaki, Japan. |
| | C2 | Pierret, Robert F., Semiconductor Device Fundamentals, Table 1.1, (1995), Addison-Wesley, page 4. |

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| Examiner | Date Considered 7/12/2005 |
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.